

Notice of References Cited

Application/Control No.

10/801,341

Applicant(s)/Patent Under
Reexamination
NELSON ET AL.

Examiner

Asok K. Sarkar

Art Unit

2891

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2004/0136891	07-2004	Kijima et al.	423/263
*	B	US-2005/0087513	04-2005	Liao et al.	216/054
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N	DD 258000A	07-1988	DDR	Heckner et al.	----
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NON-PATENT DOCUMENTS

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	V	Hosono et al., "Ecimer Laser Crystallization of Amorphous Indium - Tin - Oxide and Its Application in Fine Patterning", Japanese Journal of Applied Physics, Part 2: Letterss (1998), 37(10A), L1119 - L1121
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.